Materials Characterization : Introduction to Microscopic and Spectroscopic Methods

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The yellow marked chapters are not in the scope of the course but good additional information. They are not included for the exam. The estimated number of pages of the chapter that are relevant to the exam are (marked) and also the contact session you should study the chapter.

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**Nanoindentation paper (part of exam material)**

**“Nanoindentation Examination of Crystalline Solid Surfaces”**

1. General Introduction

2. General Remarks on Existing Models and Conventional Analyses of Depth-Sensing

Indentation Data

3. Atomistic Simulation of the Nanoindentation Process

4. Nanoindentation of Ceramics, Semiconductors, and Superconductors

5. Summarizing Remarks

Conventions and Notations